

Attorney Docket	UBAT1520
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Examiner Initials	Cite No.	FOREIGN PATENT DOCUMENTS		Publication Date MM-DD-YYYY (Number 43)	Name of Patentee or Applicant of Cited Document
		Country Code	Number Kind Code (if known)		
PK		WO 01/50201	A	07-12-2001	UT Battelle LLC
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Date Considered	07-08-2005
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PTO/SB/08B (04-03)

INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Application Number	10/649,474		
		Filing Date	August 26, 2003		
		First Named Inventor	Gregory R. Hanson		
		Group Art Unit	2877		
		Examiner Name	Unknown - Connolly		
Sheet	1	of	1	Attorney Docket Number	UBAT1520

NON-PATENT LITERATURE DOCUMENTS

PSL		International Search Report and Written Opinion, PCT/US2004/027766, February 2, 2005.	
PSX		Thomas C. E., et al. "Direct to digital holography for high aspect ratio inspection of semiconductor wafers" AIP Conference Proceedings, American Institute of Physics, New York, NY, US, no. 683, March 24, 2003, pages 254-270.	
PSL		Cuche E., et al. "Simultaneous amplitude-contrast and quantitative phase-contrast microscopy by numerical reconstruction of Fresnel off-axis holograms: Applied Optics, Optical Society of America USA, vol. 38, no. 34, December 1, 1999, pages 6994-7001.	
PSX		Cuche E., et al. "Spatial filtering for zero-order and twin-image elimination in digital off-axis holography" Applied Optics, Optical Society of America USA, vol. 39, no. 23, August 10, 2000, pages 4070-4075.	
PSL		International Search Report and Written Opinion, PCT/US2004/027749, February 2, 2005.	
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PSL		Schnars U., "Direct phase determination in hologram interferometry with use of digitally recorded holograms" Journal of the Optical Society of America - A, Optical Society of America, Washington, US, vol. 11, no. 7, July 1, 1994, pages 2011-2015.	
Examiner Signature	PATRICK CONNOLLY	Date Considered	07.08.2005

Examiner Initials	Cite No.	Document Number		Publication Date	Name of Patentee or Applicant of Cited Document
		Number	Kind Code (if known)	MM-DD-YYYY	
PJL	A1	6078392	--	06-20-2000	Thomas et al.
ML	A2	6525821	--	02-25-2003	Thomas et al.
Examiner Signature	PATRICK CONNOLLY			Date Considered	07.08.2005

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				Group Art Unit	2877
				Examiner Name	Unknown Connolly
Sheet	1	of	1	Attorney Docket Number	2500940-991520 (UBAT1520)
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ML	C1	Edgar Volkl, "Introduction to Electron Holography", pp. 133-138, published by Kluwer Academic/Plenum Publishers, New York, 1999.			
PL	C2	Jacob et al., "High Resolution Photomask Transmission and Phase Measurement Tool", Metrology, Inspection and Process Control for Microlithography XVI, Proceedings of SPIE Vol. 4689, pp. 70-82, 2002.			
FJC	C3	Thomas et al., "Direct to Digital Holography for Semiconductor Wafer Defect Detection and Review", Design, Process Integration, and Characterization for Microelectronics, Proceedings of SPIE Vol. 4692, pp. 180-194, 2002.			
ML	C4	"Phase Contrast Microscopy" Authors unknown, date unknown			
Examiner Signature		PATRICK CONNOLLY		Date Considered	07.08.2005